

1765 Jsw

U.S.S.N. 10/087,673

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Weng Chang Group Art Unit:

Serial No.: 10/087,673 Examiner: Binh X Tran

Filed: 03/02/2002 In Response to Office Action

Dated: 04/01/2004

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For: METHOD OF IMPROVING AN ETCHING PROFILE IN DUAL DAMASCENE

ETCHING

Attorney Docket No.: 67,200-691

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450.

Date: July 1/04

RESPONSE TO OFFICE ACTION

Commissioner for Patents P.O. Box 1450 Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 04/01/2004

please consider the following remarks.